



MEMS and Piezoelectric Sensors for Biomedical Applications

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Message from the Guest Editors

Dear Colleagues,

This Special Issue focuses on advanced MEMS and piezoelectric sensors research for the vital sign monitoring of wearable devices, emphasizing their advantages for wearable device design. Furthermore, the issue analyzes the contribution of continuous vital sign monitoring to the research in biomedicine and the advantages of compact wearable device design for health technology. Our primary goal is to collect research and review articles that include novel wearable device designs, scientific method-based analyses, and contributions to the biomedical field and medical technology.

We look forward to receiving your submissions!

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Editor-in-Chief

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